

# Characterization of Electronic Circuit Elements by Exclusive and Corrective Artificial Neural Networks

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**Abstract**—At present, there are many novel electronic circuit elements for which their nonlinear models for CAD are necessary, especially for microwave ones. However, in the PSpice-family programs, only a class of several classic types of the MESFET model is available for the microwave area. In the paper, a novel reliable way is suggested for modeling various electronic structures by exclusive neural networks, or by corrective neural networks working attached to a modified analytic model. The accuracy of the proposed modification of the analytic model is assessed by extracting the model parameters of GaAs MESFET, AlGaAs/InGaAs/GaAs pHEMT, and GaAs microwave varactors. First, a precise approximation of the pHEMT output characteristics is carried out by means of both exclusive and corrective artificial neural networks; and second, an approximation of the capacitance (C-V) function of the SACM InGaAs/InP avalanche photodiode is performed by the exclusive neural network. Further, the Pt-TiO<sub>2-x</sub>-Pt memristor characteristic with an extraordinary (but typical) hysteresis is approximated by a set of cooperative artificial neural networks, because a single network is unable to characterize this special element. Last, a sequence of systematic experiments is performed, which shows that the optimal structure of the network can be found relatively easily, and it should not be too complicated.

**Keywords**—Artificial neural networks, MESFET, pHEMT, microwave varactor, memristor, optimization, parameter extraction.

## I. INTRODUCTION

FOR CHARACTERIZING the electronic devices, there exist a number of models of various complexities [1]–[12], where the last two ones also contain valuable comparisons of them. In [11], both DC and capacitance parts of four models are compared using a set of measurements, and in [12], properties of DC characteristics of nine models are compared using a submicron GaAs MESFET. The realistic model of Parker and Skellern [7] can be considered most precise one, however, the identification of its model parameters is often too complicated and therefore not realized [13]. For this reason, the authors frequently seek to improve a classic model adding some function(s) with fitting parameter(s) [8]–[10], [12].

### A. Analytic Models and Using Artificial Neural Networks

Modeling of microwave devices by artificial neural networks in general is described in [14]–[18]. Various types of modeling the semiconductor devices by artificial neural networks are also described in [19]–[24] – [19] presents a neural network approach for TCAD empirical modeling, [20] presents a modeling procedure for the HEMT transistors, [21] presents MOSFET and BJT AC/DC modeling, [22] presents the small and large signal models for an AlGaAs and a SiGe HBT, [23] presents Schottky diode and pHEMT linear/nonlinear

modeling, and [24] presents a new approach to implement neural networks models for MOSFET into SPICE.

### B. Suggested Methods of Improving the Model Accuracy

First, an improvement of a classic model is suggested. The Sussman-Fort, Hantgan, and Huang [1] model equations have been selected as a good compromise between complexity and accuracy. Therefore, they can be used as an appropriate base for a corrective neural network, but both DC and capacitance part of them must be conveniently modified in advance for modeling the special microwave elements as pHEMT or varactor. The suggested improvement consists in addition of two new model parameters: the first enables characterization of possible negative output conductance, and the second enables modeling highly nonlinear capacitances of the widely various class of microwave varactors.

However, the accuracy of the modified functions is still of a percentage order in both DC and capacitance part of the model. To be more precise, using both exclusive neural network and corrective neural network with this modified analytic model can be considered an efficient and relatively simple way.

## II. MODIFYING THE ANALYTIC MODEL OF MESFET

The diagram of the MESFET model in Fig. 1 is applicable for characterizing majority of microwave transistors.

### A. Modifying the DC Part of the MESFET Model

The *primary* voltage-controlled current source of the MESFET model  $I_d$  can be defined for the forward mode ( $V_d \geq 0$ ) by standard formulae [1], [6] with a simple but efficient modification:

$$V_T = V_{T0} - \sigma V_d, \quad (1a)$$

$$I_d = \begin{cases} 0 & \text{for } V_g \leq V_T, \\ \beta (V_g - V_T)^{n_2} (1 + \lambda V_d) \tanh(\alpha V_d) & \text{otherwise,} \end{cases} \quad (1b)$$

and by mirrored equations for the reverse mode ( $V_d < 0$ )

$$V_T = V_{T0} + \sigma V_d, \quad (2a)$$

$$I_d = \begin{cases} 0 & \text{for } V'_g \leq V_T, \\ \beta (V'_g - V_T)^{n_2} (1 - \lambda V_d) \tanh(\alpha V_d) & \text{otherwise,} \end{cases} \quad (2b)$$

where  $V'_g = V_g - V_d$ . The model parameters  $V_{T0}$ ,  $\beta$ ,  $n_2$ ,  $\lambda$ , and  $\alpha$  are generally known [1], [6], the parameter  $\sigma$  used in

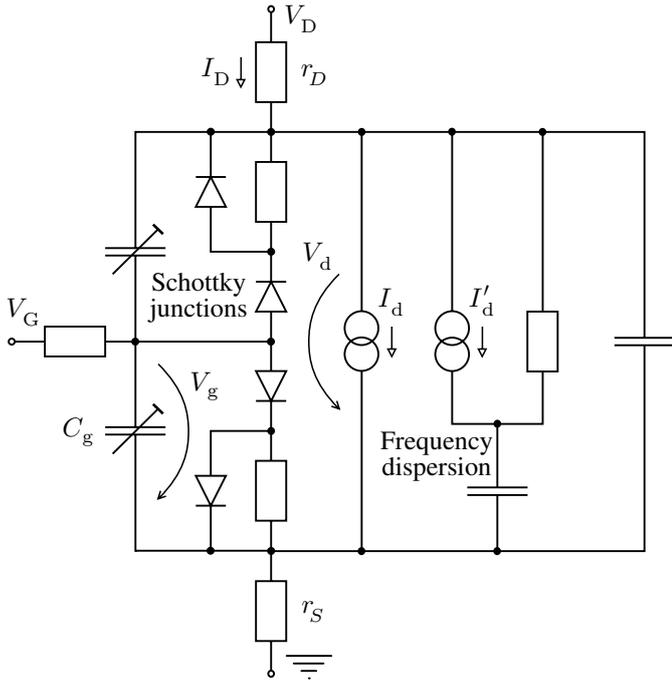


Fig. 1. Diagram of the MESFET model with the frequency dispersion.

(1a) and (2a) represents the simple but important modification necessary for modeling potential negative conductance in the MESFET output characteristics.

Although the equations (1) and (2) are relatively very simple, they contain an important improvement in comparison with the classic Curtice model [4] (by  $n_2$  parameter which characterizes gate-voltage influence on  $I_d$  more precisely), and also in comparison with the classic Statz model [2] (by  $\sigma$  parameter which characterizes drain-voltage influence on  $I_d$  more precisely).

A comparison of our model based on the slightly modified equations (1) and (2) with eight other ones is performed in [12] in a comprehensive way.

The importance of the modifications (1a) and (2a) can be clearly demonstrated by the identification of the model parameters for DZ71 MESFET [3], which is shown in Fig. 2. The C.I.A. optimization procedure [10] has determined the values of the model parameters  $V_{T0} = -1.36$  V,  $\beta = 0.0346$  A V<sup>-2</sup>,  $n_2 = 1.73$ ,  $\lambda = -0.082$  V<sup>-1</sup> (note that the negative value of this parameter sometimes arises if the parameter  $\sigma$  is used),  $\alpha = 2.56$  V<sup>-1</sup>,  $\sigma = 0.141$ ,  $r_D = 2.88$   $\Omega$ , and  $r_S = 2.62$   $\Omega$  (note that the  $r_D$  and  $r_S$  parameters have already been estimated in [3]). To compare the achievement, the parameters of the same MESFET have also been identified for the classical Statz model [2]. As shown in Fig. 2, the modified formulae are more accurate, especially for the lesser values of the gate-source control voltage, and also for the greater values of the drain current.

### B. Using the Modified Model as a PHEMT Approximation

The modifications (1a) and (2a) enable the model to be used as the pHEMT approximation, which is shown in Fig. 3. The

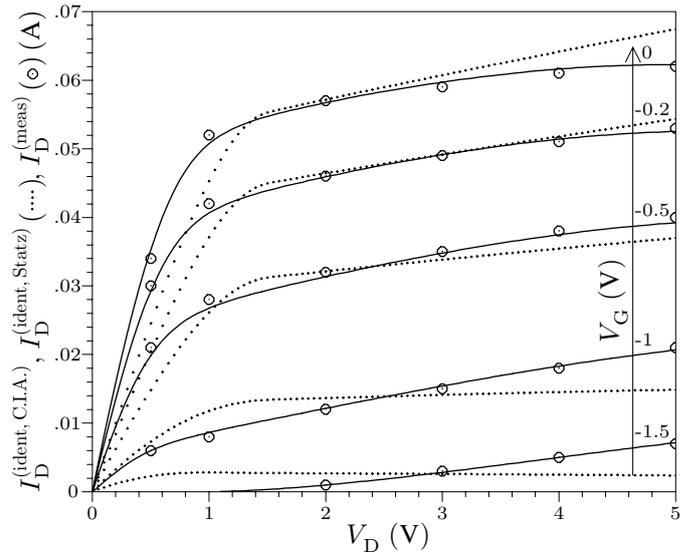


Fig. 2. Comparison of the MESFET model identification using formula (1) (continuous lines) and the classical Statz equation (dots) [2]. The root-mean-square and maximal-absolute-value deviations (see the definitions in Appendix) of the model (1) are  $rms = 2.73$  % and  $\delta_{max} = 8$  %, respectively. The measured data (circled dots) is taken from [3].

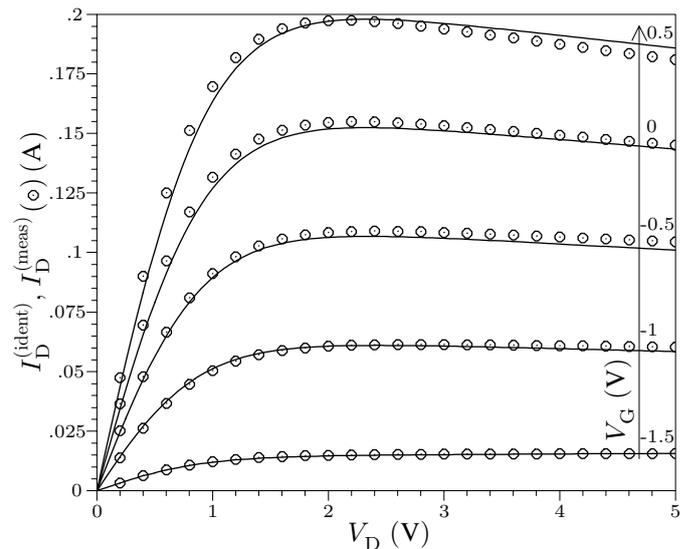


Fig. 3. Results of the AlGaAs/InGaAs/GaAs power pHEMT model identification (continuous lines) using formula (1) ( $rms = 2.38$  % and  $\delta_{max} = 8.24$  %). The measured data (circled dots) is taken from [8].

parameter extraction process has determined the values  $V_{T0} = -1.64$  V,  $\beta = 0.102$  A V<sup>-2</sup>,  $n_2 = 0.991$ ,  $\lambda = -0.0288$  V<sup>-1</sup>,  $\alpha = 1.16$  V<sup>-1</sup>,  $\sigma = 0.00797$ ,  $r_D = 0.3$   $\Omega$ , and  $r_S = 0.2$   $\Omega$ . This model represents the transistor with the rms deviation of a percentage order, and is slightly more accurate than the TriQuint one [8].

On the other hand, at very high frequencies, the values of the  $s_{22}$  parameter does *not* match the DC curves. Therefore, a *secondary* current source  $I'_d$  must be added, and its model parameters can be identified using a system of the  $s$  parameters of pHEMT at various operating points.

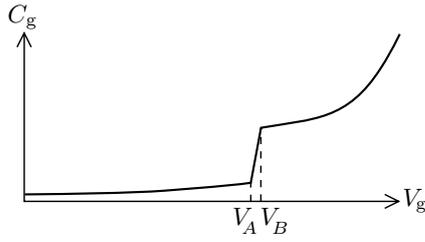


Fig. 4. Nonlinear MESFET capacitance model (for both source and drain junctions).

### C. Modifying the Capacitance Part of the MESFET Model

In general, the MESFET gate capacitances are highly nonlinear as shown in Fig. 4. The model of the gate-source capacitance splits into the three parts, similar to those in the Statz [2] and recent models [7]:

$$C_g = \begin{cases} \epsilon W \arctan \sqrt{\frac{\phi_0 - V_T}{V_T - V_g}} & \text{for } V_g \leq V_A, \\ \frac{V_g - V_A}{V_B - V_A} \left[ C_{J0} \left( 1 - \frac{V_B}{\phi_0} \right)^{-m} + \pi \frac{\epsilon W}{2} - \epsilon W \arctan \sqrt{\frac{\phi_0 - V_T}{V_T - V_A}} \right] + \epsilon W \arctan \sqrt{\frac{\phi_0 - V_T}{V_T - V_A}} & \text{for } V_g > V_A \wedge V_g < V_B, \\ \pi \frac{\epsilon W}{2} + C_{J0} \left( 1 - \frac{V_g}{\phi_0} \right)^{-m} & \text{for } V_g \geq V_B, \end{cases} \quad (3)$$

where the transitional region  $(V_A, V_B)$  is specified empirically:

$$V_A = V_T - 0.15 \text{ V}, \quad V_B = V_T + 0.08 \text{ V}. \quad (4)$$

All the model parameters have already been defined in [1] with the exception of the power  $-m$  (the classic models including the Statz one always use the theoretical value  $-\frac{1}{2}$  instead of  $-m$ ).

### D. Using the Modified Model as a Varactor Approximation

The microwave varactors are highly nonlinear with observed voltage dependencies analogical to those in the MESFET gate capacitances. Therefore, the functions in (3) can be used after replacing  $C_g$  and  $V_g$  with the external ones, i.e., with  $C_G$  and  $V_G$ . Let us emphasize that such empirical method is often used in the microwave semiconductor device modeling.

First, let us demonstrate this idea by identifying the Texas Instruments EG8132 [25] gate varactor model as shown in Fig. 5. The identification results confirm that the use of (3) enables more accurate approximation than the 6<sup>th</sup>-order polynomial in [25]. The optimization procedure of the C.I.A. program has determined the values of the model parameters  $\epsilon W = 0.15711$  pF,  $C_{J0} = 1.0771$  pF,  $V_T = -2.7569$  V,  $\phi_0 = 23.451$  V, and  $m = 12.827$ . Emphasize that the last two parameters do not have “physical” values, which clearly illustrates the necessity of using the  $-m$ -power in (3).

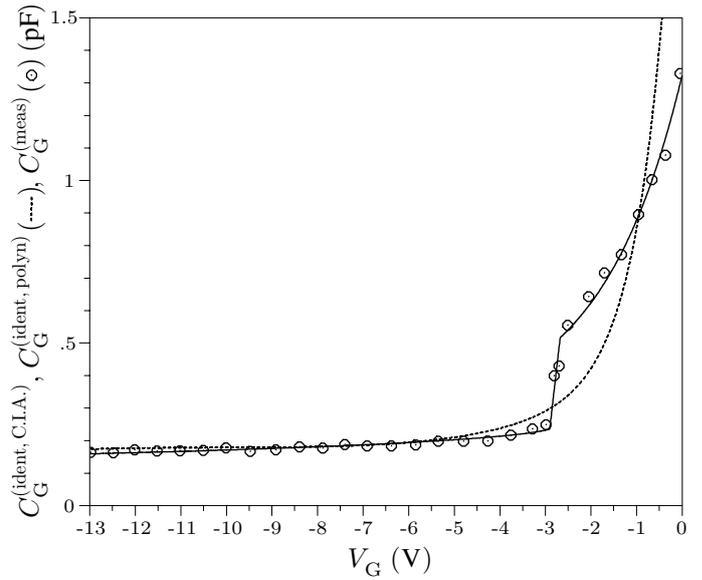


Fig. 5. Comparison of the Texas Instruments EG8132 *gate-varactor* model identification using formula (3) and a polynomial approximation (rms = 4.52 % and  $\delta_{\max} = 13.7$  % for (3)). The measured data (circled dots) is taken from [25], where the polynomial approximation  $a_0 + a_2(V_G - V_A)^{-2} + a_3(V_G - V_A)^{-3} + \dots + a_6(V_G - V_A)^{-6}$  has been demonstrated with the results drawn by the dashed line. (In [25], the parameters  $V_A = -8$  V,  $a_0 = -0.54$  pF,  $a_2 = 2.3$  nF V<sup>2</sup>,  $a_3 = -87.938$  nF V<sup>3</sup>,  $a_4 = 1.4$   $\mu$ F V<sup>4</sup>,  $a_5 = -10.458$   $\mu$ F V<sup>5</sup>, and  $a_6 = 30.48$   $\mu$ F V<sup>6</sup> have been used for the interpolation polynomial.)

Second, for the EG8132 source varactor, the optimization procedure of the C.I.A. program has determined the values of the model parameters  $\epsilon W = 0.13587$  pF,  $C_{J0} = 0.66625$  pF,  $V_T = -2.6026$  V,  $\phi_0 = 13.251$  V, and  $m = 8.1457$  with a little more precise device characterization as shown in Fig. 6 – let us compare the values rms and  $\delta_{\max}$ .

Third, the parameters of the capacitance model of the optical SACM (Separated Absorption, Charge, and Multiplication) avalanche photodiode MO457/4 (International Laser Centre [26]) have also been extracted. The optimization procedure of the C.I.A. program has determined the values of the model parameters  $\epsilon W = 1.51155$  pF,  $C_{J0} = 5.30894$  pF,  $V_T = -6.17455$  V,  $\phi_0 = 204.491$  V, and  $m = 30.4842$  with a little lesser accuracy as shown in Fig. 7. Therefore, potential improvement of this (not excellent) model using an artificial neural network is advisable, and it will be demonstrated in Section III.

## III. APPLYING THE ARTIFICIAL NEURAL NETWORKS

The rms and  $\delta_{\max}$  deviations from measured data for the analytic models can be of the percentage order, which was clearly illustrated in Section II. To obtain lesser values, the artificial neural networks can be used for modeling the devices. A detailed description of the concept of the neural networks can be found in [14] with the emphasis to modeling the nonlinear microwave devices. There can be two fundamental ways for using the artificial neural networks. The first consists in applying an exclusive neural network, i.e., it works *without* any analytic model, and the second uses a neural network

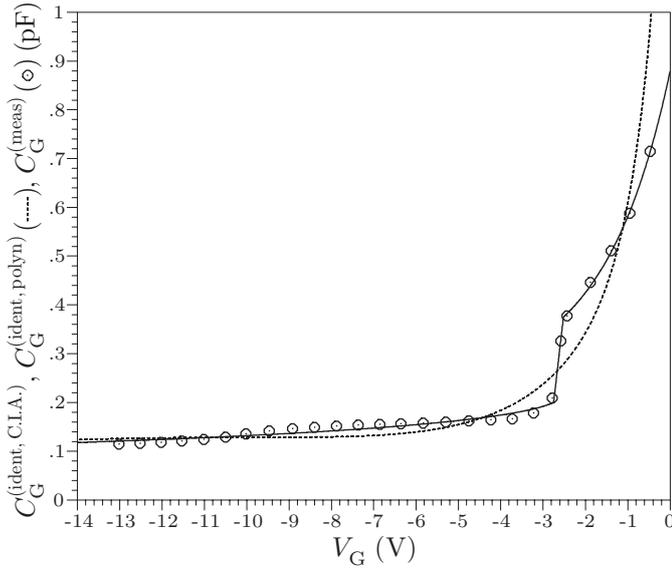


Fig. 6. Comparison of the EG8132 *source*-varactor model identification using formula (3) and the polynomial approximation (rms = 4 % and  $\delta_{\max} = 6.87$  % for (3)). The measured data and the same polynomial approximation ( $V_a = -6$  V,  $a_0 = -0.09$  pF,  $a_2 = 0.4783$  nF V<sup>2</sup>,  $a_3 = -14.703$  nF V<sup>3</sup>,  $a_4 = 0.18351$   $\mu$ F V<sup>4</sup>,  $a_5 = -1.0475$   $\mu$ F V<sup>5</sup>, and  $a_6 = 2.3177$   $\mu$ F V<sup>6</sup>) are taken from [25] again.

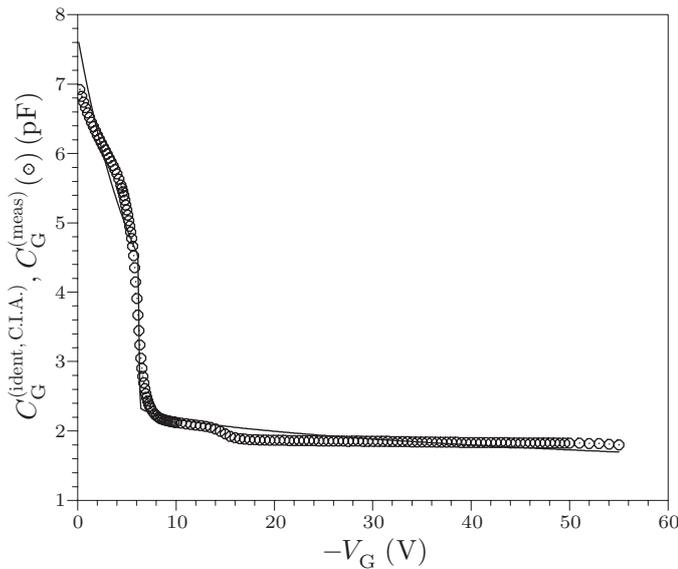


Fig. 7. Results of the MO457/4 capacitance model identification using formula (3) (rms = 6.21 % and  $\delta_{\max} = 23.7$  %). The measured data has been granted by the authors of [26].

as a correction tool for the *difference* between the measured data and the previously identified analytic model (which was suitably modified in advance).

#### A. Applying the Exclusive Artificial Neural Networks

Initially, the models identified in Section II have also been approximated using the exclusive neural networks to compare their accuracy with the modified analytic models. Regarding the exclusive artificial neural networks, the standard multilayer perceptrons (MLP) structure [14, p. 65] has been used. The

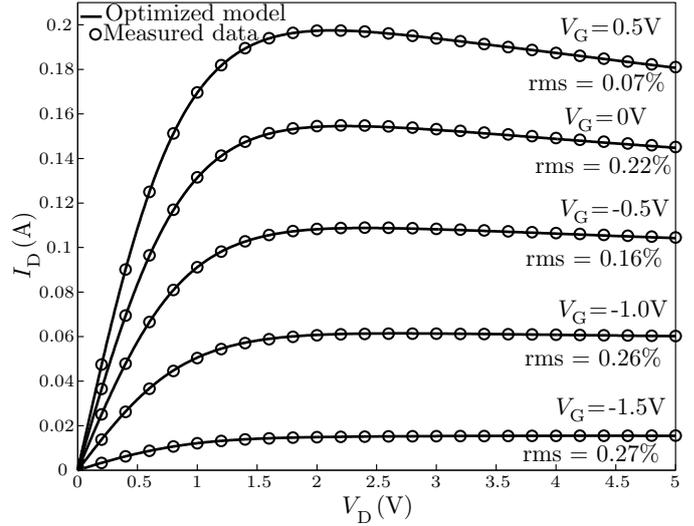


Fig. 8. Results of the pHEMT model identification using exclusive neural network of the MLP-2-5-4-5-1 structure (for all the characteristics together, rms = 0.2 %).

TABLE I  
COMPARISON OF THE ACCURACY OF THE MODIFIED ANALYTIC MODEL WITH THE MODELS CREATED BY THE EXCLUSIVE AND CORRECTIVE NEURAL NETWORKS

$V_G$ (V)	rms (%)		
	Analytic model	Exclusive	Corrective
0.5	3.23	0.07	0.0006162
0	2.68	0.22	0.0005629
-0.5	2.39	0.16	0.0014
-1	1.85	0.26	0.0362
-1.5	1.23	0.27	0.1043
All curves	2.38	0.2	0.028

number of layers and the number of neurons in these layers have been selected performing greater number of systematic numerical tests.

1) *Enhancing the Accuracy of the PHEMT Model:* The exclusive artificial neural network has also been used for modeling the pHEMT with the results shown in Fig. 8 and the third column of Table I. A relatively simple structure MLP-2-5-4-5-1 has been selected. As shown in Table I, the accuracy of the exclusive neural network (rms = 0.2 %) has been approximately ten times better than that for the modified analytic model (rms = 2.38 %).

2) *Enhancing the Accuracy of the Varactor Model:* The optical SACM avalanche photodiode MO457/4 [26] model should be replaced by a neural network because the approximation by the analytic function (3) was not ideal (the values of rms and  $\delta_{\max}$  mentioned in Fig. 7). For characterizing this photodiode, a simple structure MLP-1-4-5-4-1 has been used with the result shown in Fig. 9. Let us emphasize that the accuracy of this exclusive neural network is sufficient – hence, there is no need to use a corrective neural network in a combination with the analytic model here.

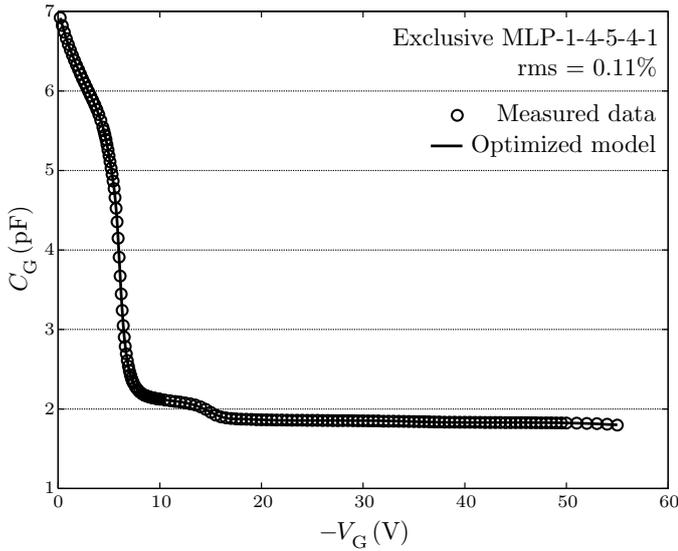


Fig. 9. Results of the MO457/4 capacitance model identification using exclusive neural network ( $\delta_{\max}$  is only 0.4 %).

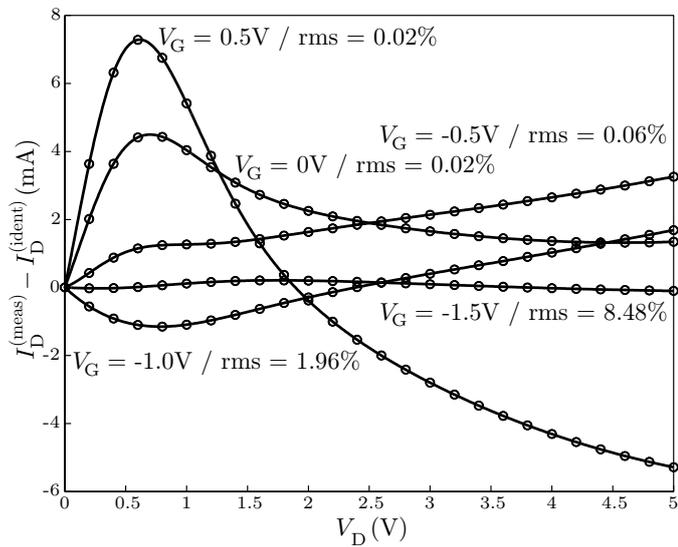


Fig. 10. Results of the approximation of the differences between the measured data and (previously identified) modified analytic model (that is shown in Fig. 3), which is an outcome of the corrective neural network MLP 2-8-10-6-1. (1000 training epochs have been used.)

### B. Applying the Corrective Artificial Neural Network

In Fig. 10, only the *differences* between the pHEMT measured data and previously identified analytic model are shown (circles) and approximated using a corrective neural network (continuous lines). (In other words, in the first step an analytic model is identified, and its model parameters are extracted. After that, an error of the analytic model is evaluated. Finally, this error is compensated by a neural network.) The resulting accuracy of the modified analytic model with this corrective neural network is shown in the last column of Table I (the analytic model and corrective neural network operate together and therefore their final rms is much lesser than the rms of the differences). This methodology gives the best accuracy.

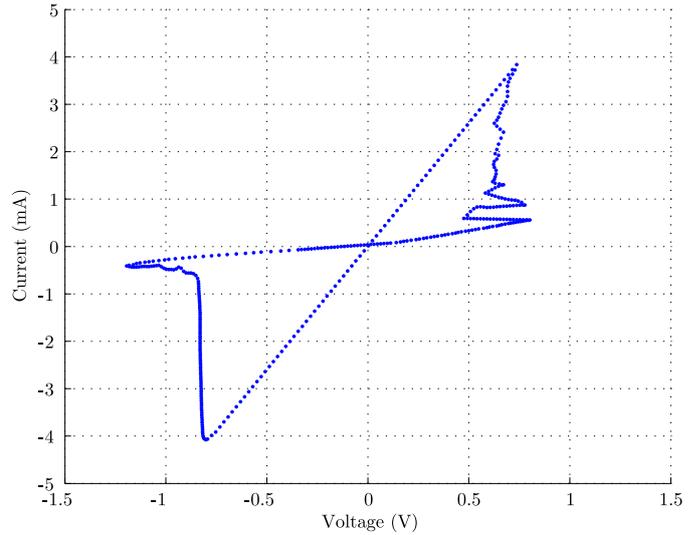


Fig. 11. Measured characteristic of a Pt – TiO<sub>2-x</sub> – Pt memristor. Original characteristic and other technological data are described in all details in [27].

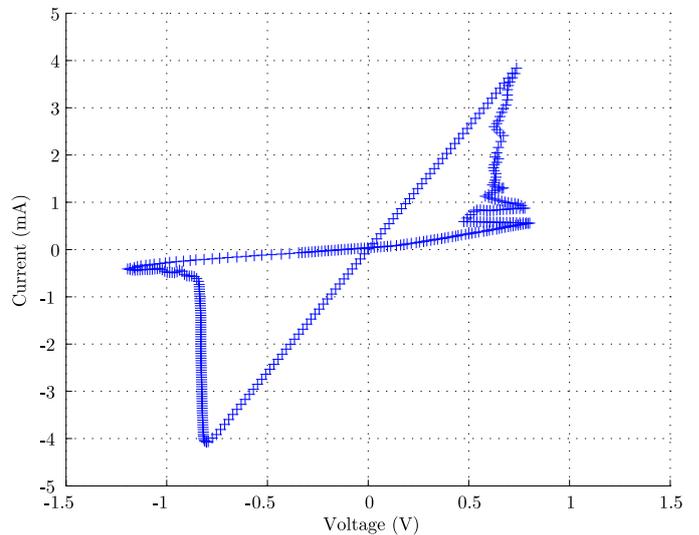


Fig. 12. An approximation of the memristor with a set of cooperative artificial neural networks, both  $y = f(x)$  and  $x = f(y)$  types of the networks are necessary because any single network is unable to characterize it precisely.

### C. Applying the Cooperative Artificial Neural Networks

In Fig. 11, a set of measured points for a Pt – TiO<sub>2-x</sub> – Pt memristor [27] is depicted. There are some analytic approximations of this characteristic with an extraordinary hysteresis and several irregularities [27], [28], but the precision of these simple models is limited. Such an element is very difficult to be characterized especially with respect to the fact that it is neither  $y = f(x)$  nor  $x = f(y)$  function. For this reason, the element has been approximated by *more* cooperative networks, some of them of  $y = f(x)$  and another one of  $x = f(y)$  types.

The result of the usage of the set of the neural networks is shown in Fig. 12. For the comprehensive characterization of the memristor, the MLP-1-2-3-2-1 ( $y = f(x)$ , the low-resistance linear part), MLP-1-4-5-3-2-1 ( $x = f(y)$ , the most complicated part on the right), MLP-1-5-7-3-1 ( $y = f(x)$ , the

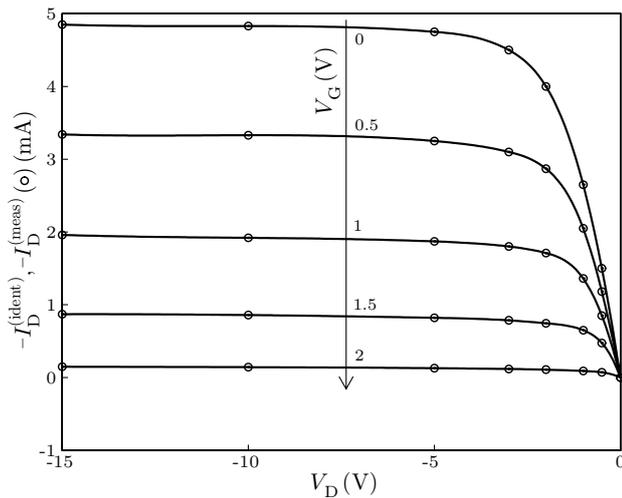


Fig. 13. Results of the identification of the model of 2N2498 PJFET. The measured data is taken from [29] (circled dots), and additional points have been calculated by local interpolation polynomials.

analogical part on the left), and MLP-1-3-4-2-1 ( $y = f(x)$ , the high-resistance linear part) networks have been used, i.e., three or four (due to the most complicated part) internal layers have been necessary. As shown, the set of the cooperative networks is able to approximate the memristor in a quite precise way.

#### IV. CHOICE OF AN OPTIMAL STRUCTURE OF NEURAL NETWORK

Determining the number of layers and the number of elements in these layers for a neural network is not a simple task. In this section, four illustrative examples are solved – two ones for a two-port device with “normal” characteristics, and two ones for a two-port device with “abnormal” characteristics (with the negative output conductance and the dependence of the threshold voltage on the drain-source voltage). Optimal neural networks have been found by a systematic searching.

##### A. Searching for the Optimal Structure for the PJFET Model

The first two examples illustrate searching for an optimal structure for a device with “normal” output characteristics – for this reason, the classic 2N2498 PJFET [29] has been selected. A sequence of the identifications has been performed for the five- and four-layer structures.

The five-layer exclusive artificial neural network has been chosen in the first example and the number of elements has been investigated for the 2<sup>nd</sup>, 3<sup>rd</sup>, and 4<sup>th</sup> layer as shown in Table II.

As demonstrated in Table II, the simplest and the most complicated networks are unstable because the networks with more training epochs give worse results. Moreover, the simpler networks sometimes give slightly better results than the more complicated ones. The best results have been found for the MLP-2-5-7-7-1 structure utilizing 1000 training epochs – see Fig. 13.

The four-layer exclusive artificial neural network has been chosen in the second example [30] and the number of elements

TABLE II  
SYSTEMATIC SEARCHING FOR THE OPTIMAL NUMBER OF ELEMENTS IN THE FIVE-LAYER ARTIFICIAL NEURAL NETWORK FOR PJFET 2N2498

Type of network	Relative deviations of networks with 500/1000 training epochs	
	rms (%)	$\delta_{\max}$ (%)
MLP-2-2-2-3-1	11.03/23.84	122.7/243.0
MLP-2-3-3-3-1	1.579/1.375	13.40/8.058
MLP-2-3-5-3-1	7.166/0.8278	29.20/4.097
MLP-2-3-5-5-1	1.945/0.3553	7.476/1.528
MLP-2-3-7-5-1	0.9845/0.3078	7.043/1.600
MLP-2-3-7-7-1	2.431/1.108	15.72/10.20
MLP-2-5-7-7-1	0.1880/0.0921	1.356/0.6242
MLP-2-5-10-7-1	0.1144/0.1803	0.6546/1.407

has been investigated for the 2<sup>nd</sup> and 3<sup>rd</sup> layer as shown in Table III.

As demonstrated in Table III, the simplest and the most complicated networks are not optimal again – instead of them, there exist relatively not too complicated structures which can be easily used with sufficient accuracy.

##### B. Searching for the Optimal Structure for the PHEMT Model

The similar tests as those for the PJFET have been performed for the AlGaAs/InGaAs/GaAs power microwave pHEMT. First, a five-layer structure is tested. The results are summarized in Table IV. The rms error is the best for the structure MLP-2-8-8-6-1. However, the overall results are better for the simpler structure MLP-2-4-6-4-1 because it's lesser value of  $\delta_{\max}$  – for this reason, this structure can be considered the best result for the five-layer structure.

The good values rms and  $\delta_{\max}$  promise that even simpler network can be used. In Table V, the results for the four-layer network are summarized. For this network, a more systematic procedure has been used that goes through all possible network configurations. The rms error is the best for the structure MLP-2-4-6-1. However, the very accurate results are also obtained for another similar structure MLP-2-3-7-1, so we can obtain several networks which get sufficiently accurate results.

The results in Tables IV and V validate again that the optimal structure should not be too complicated.

The systematic searching for an optimal structure of the artificial neural networks confirms that the four-layer structures can be considered a suitable choice, i.e., the structures with two internal layers with no more than ten elements (which is in accordance with [31]).

#### V. CONCLUSIONS

The experiments confirm that the precision of the analytic models cannot be better than of a percentage order. Enhancing the precision is possible and relatively easy by artificial neural networks. Using the exclusive artificial neural networks gives the precision of tenths of percent. However, the most accurate way consists in the combination of the modified analytic model with the corrective artificial neural network. Both analytic model parameters and neural network weights can easily

TABLE III

SYSTEMATIC SEARCHING FOR THE OPTIMAL NUMBER OF ELEMENTS IN THE **FOUR-LAYER** ARTIFICIAL NEURAL NETWORK FOR PJFET 2N2498

Type of network	Relative deviations of networks with 500 training epochs	
	rms (%)	
MLP-2-2-2-1	12.17	
MLP-2-2-3-1	5.708	
MLP-2-2-4-1	1.332	
MLP-2-2-5-1	0.7997	
MLP-2-2-6-1	5.919	
MLP-2-2-7-1	0.8596	
MLP-2-2-8-1	1.689	
MLP-2-2-9-1	0.3682	
MLP-2-3-2-1	1.329	
MLP-2-3-3-1	0.3694	
MLP-2-3-4-1	0.273	
MLP-2-3-5-1	0.4027	
MLP-2-3-6-1	0.2996	
MLP-2-3-7-1	0.1472	
MLP-2-3-8-1	<u>0.0492</u>	
MLP-2-3-9-1	0.5524	
MLP-2-3-10-1	0.2733	
MLP-2-3-11-1	0.6381	
MLP-2-4-2-1	0.4998	
MLP-2-4-3-1	0.0544	
MLP-2-4-4-1	0.4026	
MLP-2-4-5-1	0.2052	
MLP-2-4-6-1	0.1112	
MLP-2-4-7-1	0.0866	
MLP-2-4-8-1	0.7896	
MLP-2-4-9-1	0.0467	
MLP-2-4-10-1	<u>0.0144</u>	
MLP-2-4-11-1	0.0506	
MLP-2-4-12-1	0.0191	
MLP-2-5-2-1	0.3074	
MLP-2-5-3-1	0.5524	
MLP-2-5-4-1	0.1543	
MLP-2-5-5-1	<u>0.0294</u>	
MLP-2-5-6-1	0.0387	
MLP-2-5-7-1	0.0315	
MLP-2-5-8-1	0.0328	
MLP-2-5-9-1	0.0332	
MLP-2-5-10-1	0.0453	
MLP-2-5-11-1	0.1387	
MLP-2-6-2-1	0.4822	
MLP-2-6-3-1	0.0482	
MLP-2-6-4-1	0.1381	
MLP-2-6-5-1	0.0236	
MLP-2-6-6-1	0.0426	
MLP-2-6-7-1	0.0284	
MLP-2-6-8-1	0.0328	
MLP-2-6-9-1	0.0432	
MLP-2-6-10-1	0.0596	
MLP-2-6-11-1	<u>0.018</u>	
MLP-2-6-12-1	0.0488	

TABLE IV

SYSTEMATIC SEARCHING FOR THE OPTIMAL NUMBER OF ELEMENTS IN THE **FIVE-LAYER** NEURAL NETWORK FOR PHEMT FROM PCS CDMA

Type of network	Relative deviations of networks with 500 training epochs	
	rms (%)	$\delta_{max}$ (%)
MLP-2-2-2-2-1	3.781	57.75
MLP-2-2-4-2-1	1.891	16.91
MLP-2-2-4-4-1	0.1363	0.8966
MLP-2-4-4-4-1	0.0233	0.2150
MLP-2-4-6-4-1	0.0204	<u>0.1607</u>
MLP-2-4-6-6-1	0.1788	3.065
MLP-2-6-6-6-1	0.2588	1.272
MLP-2-6-8-6-1	0.0368	0.2614
MLP-2-8-8-6-1	<u>0.0057</u>	0.3452
MLP-2-8-10-6-1	0.0386	0.7587

TABLE V

SYSTEMATIC SEARCHING FOR THE OPTIMAL NUMBER OF ELEMENTS IN THE **FOUR-LAYER** NEURAL NETWORK FOR PHEMT FROM PCS CDMA

Type of network	Relative deviations of networks with 500 training epochs	
	rms (%)	$\delta_{max}$ (%)
MLP-2-2-2-1	12.02	192.2
MLP-2-2-3-1	5.683	91.11
MLP-2-2-4-1	2.271	14.98
MLP-2-2-5-1	4.742	36.08
MLP-2-2-6-1	0.9973	<u>7.196</u>
MLP-2-2-7-1	2.78	37.67
MLP-2-2-8-1	<u>0.7249</u>	9.49
MLP-2-3-2-1	0.8675	5.982
MLP-2-3-3-1	1.418	10.46
MLP-2-3-4-1	0.4432	5.532
MLP-2-3-5-1	0.552	5.728
MLP-2-3-6-1	1.866	14.06
MLP-2-3-7-1	<u>0.0422</u>	<u>0.8029</u>
MLP-2-3-8-1	1.024	7.29
MLP-2-4-2-1	1.214	13.91
MLP-2-4-3-1	0.2465	2.235
MLP-2-4-4-1	0.3087	4.255
MLP-2-4-5-1	0.0829	1.337
MLP-2-4-6-1	<u>0.0331</u>	0.5998
MLP-2-4-7-1	0.1378	2.342
MLP-2-4-8-1	0.0427	<u>0.4804</u>

be extracted using implemented optimization procedure – however, the neural networks typically need **more measured points** for a smooth interpolation of elements. For the elements with hysteresis and irregularities, an original method is suggested based on more cooperative networks. A sequence of experiments has also been performed, which has demonstrated that the optimal structure of the network should not be too complicated. Generally, **two internal layers** are recommended with usually **4–8 elements per one internal layer**. The next work will be devoted to an **automation of choice processes**.

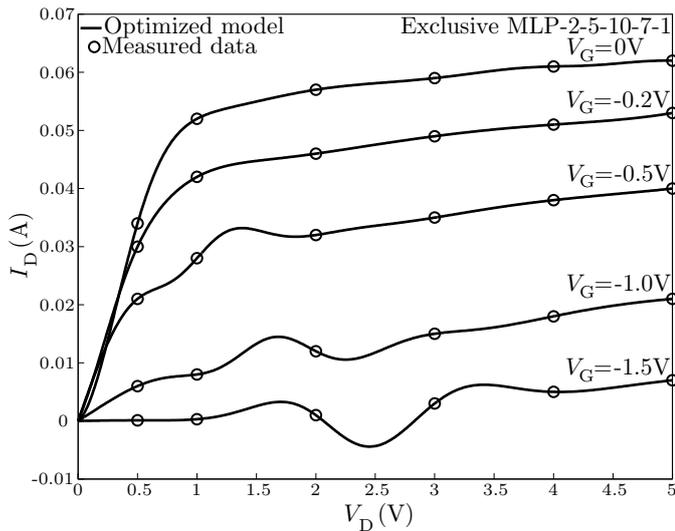


Fig. 14. Incorrect results of the DZ71 MESFET model identification caused due to an insufficient number of the measured points.

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#### APPENDIX

The **root-mean-square** and **maximal-absolute-value** deviations are defined by the formulae

$$\text{rms} = \sqrt{\frac{\sum_{i=1}^{n_p} \left( \frac{y_i^{(\text{ident})} - y_i^{(\text{meas})}}{y_i^{(\text{meas})}} \right)^2}{n_p}} \times 100 \%$$

and

$$\delta_{\max} = \max_{i=1, \dots, n_p} \left| \frac{y_i^{(\text{ident})} - y_i^{(\text{meas})}}{y_i^{(\text{meas})}} \right| \times 100 \%,$$

respectively, where  $y_i^{(\text{ident})}$  and  $y_i^{(\text{meas})}$  mark the identified and measured values, respectively, and  $n_p$  is the number of points.

The artificial neural networks must be used cautiously. The **devices must be measured in sufficient number of points**. Otherwise, we could obtain bizarre results as shown for the DZ71 MESFET model identification in Fig. 14 – certainly, the number of measured points is totally insufficient for training.

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